

Semicon Synapsis

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MX-R High power inspection microscope



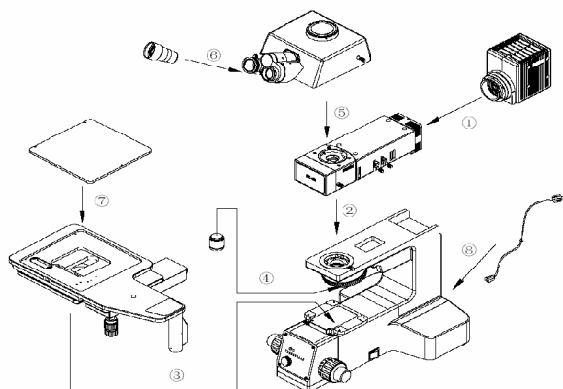
MX-R High power inspection microscope

The new MX-R, available in 6 and 8" versions, is the most cost effective solution for wafer micro inspection needs. It can be used as a normal microscope or equipped with many accessories, such as our SemiMap system for the most advanced inspection management.

Specifications	
Optical System	Color corrected infinity optical system (CCIS)
Eyepieces	PL10X 23T high point plan eyepiece with adj. ring, view field \varnothing 23 mm PL10X 22 high point plan eyepiece, view field \varnothing 22 mm PL15X 16 high point plan eyepiece, view field \varnothing 16 mm Special eyepieces on request
Head	25° inclined gemel trinocular head with vertical image, prismatic rate 100% for binocular, 100% for trinocular
Nosepiece	Built-in quintuple nosepiece with BF and DF
Objective	Infinity long working distance plan achromatic metallography objective 10X/0.25/6, 20X/0.4/5, 50X/0.7/2, 80X/0.8/1 - all for BF and DF
Focusing	Fine and coarse coaxial, 33mm range, 0.001 mm precision
Illuminator	Reflected Kohler illuminator with BF and DF (can be used with simple polarizing kit) 12V 100W with digital brightness adjustment and light renew function
Stage	6" or 8" mechanical stage (depending on versions) with low hand adjustment and clutch for swift movement
Accessories	Simple polarizing kit, interference filter and micrometer, TV devices, motorized X/Y/R stage with vacuum chuck, SemiMap wafer map management software with autofocus and OCR reader (only with motorized stage - ask for more details)

(Specifications are subject to change without any obligation on the part of manufacturer)

MX System Diagram



External Dimensions (6" version)

